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Late 1980s

Fully automatic fab

~ Discrete Semiconductor/Others ~

Integration level had been progressed and capacity of DRAMs had been increased in the 1980s. The generation shifted from the kilobit to the megabit class and production volume also increased dramatically. Therefore, it was desirable to build a more efficient factory. Automation of production lines was also an inevitable requirement of the era. In particular, in the wafer fabrication process, which was based on cassette-to-cassette wafer transfer system and job-shop fabrication system, a wide variety of technologies had been established, including fabrication equipment, wafer transfer/conveyer system, robots, and computer control systems, which also served as the basis for automation. On the other hand, the evolution of clean technology, which was directly related to yield, was also remarkable in progress.



Figure 1 Saijo Works



Figure 2 Wafer Transfer Robot

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